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Summary

This paper summarizes the progress during the last several years in the technology of sources of high charge state positive heavy ions and negative heavy ions. Subjects covered include recent results in BE and EBIS source development and comparison of various source types for high charge state heavy ions.

Introduction

The ideal ion source for a modern heavy ion accelerator should provide beams of all atomic species of high intensity, good emittance and long lifetime. The source should be easily accessible for maintenance. For cyclotrons and linear accelerators, which require positive ions from the source, high charge states are desirable because the cyclotron energy is proportional to charge squared, and linac length can be reduced by using ions with higher charge states. For tandem electrostatic accelerators the charge state is -1. (Only a few low intensity ion species have been produced with -2 charge).

Positive Heavy Ion Sources

High charge state ion beams for positive ion accelerators can be produced by electron bombardment of atoms and ions in a plasma or by stripping of fast ions in a foil or gas. Electron bombardment sources were previously reviewed by Vorobev and Pasyuk,<sup>1</sup> Bennett,<sup>2</sup> Eninger,<sup>3</sup> Septier,<sup>4</sup> Winter and Wolf,<sup>5</sup> and Arianer.<sup>6</sup>

For electron bombardment sources the product of the flux density  $J_0$  and ion confinement time  $T_1$  must be sufficient to produce the desired charge state  $q$ . Also the electron energy distribution should include the region of peak ionization cross-section, which occurs at several times the ionization potential. So electron energies should be 10's of eV up to hundreds or several thousand eV. Figure 1, updated from a figure of Winter and Wolf<sup>5</sup> and Clark,<sup>7</sup> shows the operating ranges of several types of heavy ion sources. The sources with higher  $nT_1$  produce higher charge states. The principal types of heavy ion sources will be described below. Many examples are described in the two Gatlinburg Conferences on heavy ion sources, References 8 and 7.

PIG Sources:

The traditional heavy ion source for cyclotrons and linacs is the PIG (Penning or Phillips Ion Gauge). The principles and designs used by various laboratories were reviewed in the last several years by Bennett,<sup>8</sup> Green,<sup>9</sup> Makov,<sup>10</sup> and Schulte et al.<sup>11</sup> The first PIG source used in a cyclotron was built by Jones and Zucker<sup>12</sup> at Oak Ridge in 1954 for  $N^{3+}$ . Later sources were built by Anderson and Ehlers<sup>13</sup> for the Berkeley and Yale HILACS and by Morosov, Makov and Ioffe<sup>14</sup> for cyclotrons. Many other groups have built PIG sources, mostly for cyclotrons, but most of the designs are similar to those mentioned above.

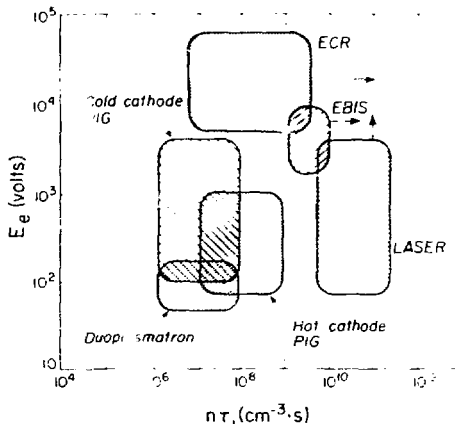


Fig. 1. Plasma parameters of high charge state ion sources.  $E_e$  is electron temperature,  $n$  is electron density,  $T_1$  is ion confinement time.

TABLE I. IONS AND INTENSITIES

SOURCE	$*q$		PEAK OUTPUT ALL $q$ 's PART/SEC	DUTY FACTOR	REF.
	NEON	XENON			
PIG	2	4	$10^{15}$ - $10^{17}$	.02-1.0	8
DUOPLASMATRON	1	3	$10^{15}$ - $10^{17}$	.03-1	20, 21
ECR-1 STAGE	2	4	$10^{16}$	.3-1.0	24
3 STAGES	5	8	$10^{14}$	.3-1.0	24
EBIS	8-9	24	$a. 10^{10}$ - $10^{11}$	$10^{-4}$	25,
			$b. 10^{13}$ - $10^{14}$		26

\* $q$  weighted by part/sec.

a. Average output over long times, assuming 10 pulses/sec.

b. Output during 100  $\mu$ sec,  $10^9$ - $10^{10}$  part/pulse.

MASTER

One of the most highly developed PIG sources is that of Pasyuk and Tretyakov at Dubna, shown in Fig. 2.<sup>15</sup> Here we see the arc chamber where the arc is struck between the two cathodes. The filament electron bombardment heating of the upper cathode provides control of the cathode temperature, and thus emission current, giving good control of arc impedance. The electrons are reflected by the cathodes for about 100 traversals. In other PIG source designs, both cathodes may be hot, or both may be cold. If both are cold, the electrons are emitted by secondary emission from ion bombardment of the cathodes. The arc parameters in various sources are 1-20 amps peak and 300-2000 volts, d.c. or pulsed. An extraction electrode is mounted close to the beam slit, with a voltage of 10-100 kV.

Solid materials can be fed into the source by placing them in a cathode, in a block tangent to the bore in the anode (Fig. 2), or by use of an oven. Pasyuk and Tretyakov<sup>15</sup> use an electrode tangent to the arc bore near the extraction slit, biased negative to sputter out the solid feed material with arc ions. Gavin at Lawrence Berkeley Laboratory<sup>16</sup> uses a similar system for the SuperHILAC 2.5-MV source. In addition Gavin found that the output of a very high charge state,  $Au^{9+}$ , can be increased by a factor of 3 by using two sputtering electrodes above and below the slit, rather than 1 electrode at the slit.

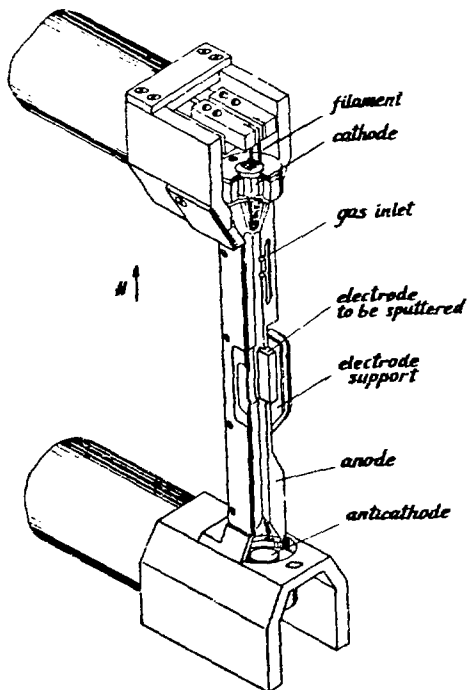


Fig. 2. Internal cyclotron PIG source of Pasyuk and Tretyakov, Lihna.<sup>15</sup>

Hudson et al.<sup>17</sup> found that solid materials can be efficiently fed into the arc of an internally heated source by using sputtering with low charge state heavy ions which reverse in the rf field. A block of the desired material is placed opposite the slit.

The PIG source gives usable beams of charge states up to  $N^{5+}$ ,  $Ne^{4+}$  and  $Ar^{8+}$ . Performance is briefly summarized in Table 1. It is still the standard source for heavy ion cyclotrons, and for heavy ion linacs, except that the dioplasmatron is used for the lighter ions at the UNILAC at Darmstadt. The lifetime between source changes is a few hours up to a day, at high duty factor operation. Future developments of the PIG source include operational use of mirror magnetic fields as developed by Haxel<sup>18</sup> and investigating possible higher charge state performance in the 40-50 keV field of future superconducting cyclotron magnets.<sup>18</sup>

#### Duoplasmatron Sources

The duoplasmatron has been used for heavy ion production by the groups of Von Ardenne<sup>19</sup> and the UNILAC group at Darmstadt. The ENILAC work has been described by Ilgen<sup>20</sup> and by Keller and Muller.<sup>21</sup>

The duoplasmatron developed by Keller and Muller for  $Xe^{6+}$  is shown in Fig. 3.<sup>21</sup> The cathode-anode voltage is 250 volts, and arc current is 7 amp. Duty factor is 25%. The magnet coil and some steel source components provide an axial magnetic guide field. Keller and Muller found that the output of  $Xe^{57+}$ <sup>11+</sup> was greatly increased by placing the position of the maximum magnetic field at the anode aperture instead of between anode and intermediate electrode. Also the anode shield is directly water cooled. Reducing the diameter of the intermediate electrode aperture increases the voltage, which gives higher charge states. Extraction is at 20-50 kV. Recently Richter and Zajec have developed a duoplasmatron with 20 mA of neon  $Ne^{3+}$ <sup>22</sup> and 17 mA of xenon.<sup>23</sup> The xenon beam looks like a promising candidate for injection into an rf linac for heavy ion fusion.<sup>24</sup>

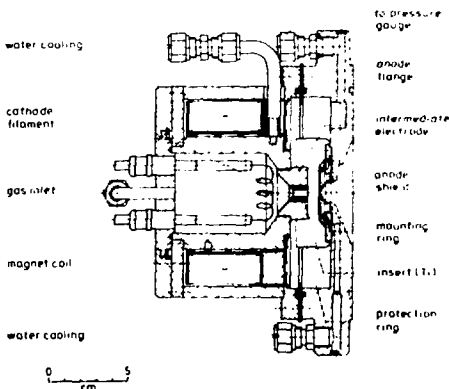


Fig. 3. Duoplasmatron source developed at GSI, Darmstadt for  $Ar^{2+}$  and  $Xe^{6+}$  by Keller and Muller.<sup>21</sup>

to be injected into the source by use of an oven.

As shown in Table 1, the duoplasmatron has as high intensity as the PIG, but lower average charge state. The emittance and lifetime is better than that of the EIL, and the equal beam shape in the two transverse planes from the duoplasmatron is an advantage for placing the source directly on an acceleration column. The UNILAC heavy ion linear has found that the duoplasmatron is preferred over the PIG for the lighter than xenon, with their requirement of charge state  $\approx 10,000$ .

#### Electron Cyclotron Resonance (ECR) Sources

Another type of source which is under development for high charge states is the electron cyclotron resonance source. Here the high energy electrons are produced by heating in microwave energy at the cyclotron resonance frequency of the electrons in the plasma. This system confines the plasma. The ECR source has been developed at Oak Ridge, Harburg, and elsewhere. The group at Grenoble under R. Geller has made great improvements<sup>24</sup> in the ECR source in the last several years. The work of the other groups is not reported in other parts of Ref. 7. The latest generation source, called TRIPLEMAPIOS, is shown in Fig. 4. An axial magnetic guide field is provided to assist in a system 3 meters long. Plasma is created by rf power in the first stage. The plasma drifts along the axis through stage 2 where ionization to high charge state takes place at a second rf section. A pressure of  $10^{-6}$  torr in stage 1 is necessary to create plasma and differential pumping gives  $10^{-9}$  torr in stage 2 to prevent recombination of the high charge state.

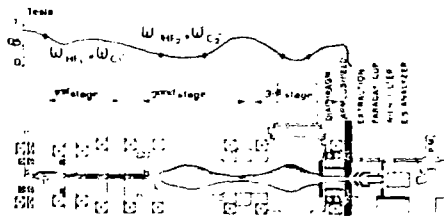


Fig. 4. ECR three stage source "TRIPLEMAPIOS." Geller.<sup>24</sup>

Table 1 shows two ECR sources. The first is one stage only, referred to as "MAPIOS" by Geller. This gives output currents and charge states similar to those of the PIG. The lifetime is weeks or months. The 3 stage source in Table 1, TRIPLEMAPIOS, shows an average charge state about twice that of the PIG for neon and xenon, but at 100 times lower intensity.

Recent progress at Grenoble<sup>24</sup> includes production of beams of  $\text{Ar}^{13+}$  at  $2 \times 10^{13}$  part./sec. and  $\text{Xe}^{18+}$  at  $10^{12}$  part./sec. with TRIPLEMAPIOS, and good emittance. A superconducting coil is proposed to reduce the power from its present megawatt level, and to increase the rf frequency and thus the plasma density. Also experiments have been done on uranium beams. One stage has been used to produce 100  $\mu\text{A}$  total uranium beam, including 50  $\mu\text{A}$  of  $\text{U}^{31+}$ . Charge states 1-6 were observed. A run with uranium beam lasts at least one day without maintenance.

The ECR source could be used to inject heavy ions with an external axial or radial injection system, to obtain higher energies.

#### Electron Beam Ion Sources (EBIS)

The electron beam ion source has been pioneered by Donets at Dubna<sup>25</sup> and also developed at Orsay, Frankfurt, Texas A&M, and Giessen. Work of all the laboratories is summarized in papers at the 1971 Galinovic Conference Ref. 25. The principles of operation of the EBIS of Donets are shown in Fig. 5. A superconducting solenoid of 1 meter length creates an electron beam from a gun placed inside the solenoid at one end. The magnetic field along the beam is limited to a radius of several millimeters as it drifts down the solenoid axis to the collector at the other end. Gas is ionized and confined electrostatically by the electron beam. A potential well formed by the drift tubes confines the ions longitudinally for typically 10-100 milliseconds, until the desired charge state is reached. The potential barrier is lowered at the solenoid exit, providing beam extraction. Beams observed<sup>25</sup> include xenon with average charge state of  $\text{Xe}^{24+}$ , and neon with  $10^8$   $\text{Ne}^{16+}$ .<sup>26</sup> The performance is summarized in Table 1. Recently the EBIS source of Donets<sup>25</sup> has shown an average charge of  $\text{Ar}^{16+}$  with about 20%  $\text{Ar}^{17+}$ .

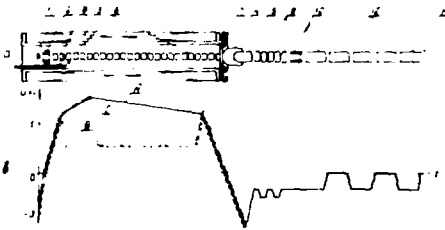


Fig. 5. EBIS source KRION-1 of Donets, Dubna.<sup>25</sup> In upper view, electron beam passes from gun (1,2) through drift tubes (6) to collector (4). Charge States are analyzed by time-of-flight system (9,10,11,12). In lower view, potential distribution along axis is that of (B) during injection, (C) during ionization and (A) for extraction.

At Orsay<sup>27</sup> SILFEC II EBIS is designed with an external electron gun of 100-800 A/cm<sup>2</sup>, injection and extraction solenoids, and a liquid helium cryopanel. Its goal is to produce fully stripped ions up to  $\text{Ca}^{20+}$  in the CW mode for a synchrotron. Electron beam tests are about to begin. The CRYEBIS with superconducting solenoid is expected to begin beam tests later in 1977.

The group of Becker and Klein at Frankfurt<sup>28</sup> are developing TOPEBIS with continuous extraction, and a containment EBIS with cold bore superconducting solenoid for the UNILAC linear at Darmstadt. The EBIS source at the Texas A&M Cyclotron Institute has recently come into preliminary operation<sup>24</sup> with extracted ion beam of  $10^8$  charge pulse and a vacuum of  $10^{-9}$  torr. Charge distribution measurements are planned for the near future.

The EBIS source requires high technology in construction, with a superconducting solenoid preferred, and vacuums of  $10^{-10}$  torr required for high charge states. Table I shows that the EBIS has the highest average charge states of the sources listed. The output current averaged over long times is orders of magnitude less than for the other sources, but the unique high charge states would make possible significant higher energies from cyclotrons than with the other sources. Also, the pulsed nature of the source and fully stripped ions, up to now presently, make it a good match to those synchrotron light sources which are designed for ions of charge mass  $\approx 1/2$ .

#### Multiple Aperture Sources

High currents of low charge state ions are produced by the multiple aperture sources developed for the production and for injection of multi-ampere beams into present and thermonuclear fusion reactors. A summary of the sources for ion propulsion of space vehicles is given by Stuhlinger.<sup>30</sup> The ions used are either cold or hot particles. The types of sources include contact ionization sources for  $\text{Cs}^+$ ,  $\text{Xe}^+$  and  $\text{Li}^+$ ; ionization sources for  $\text{H}^+$  and a hollow needle spray source for cold neutral particles. Accelerated external systems are used. The beam is neutralized just after extraction. Many sources have been designed, with diameters of 5 to 150 cm, beam currents of 0.1 to 25 amperes, and beam energies of 100 eV.

A multiple aperture source designed for high intensity hydrogen beams, was run at Lawrence Berkeley Laboratory with xenon gas by Mobley<sup>31</sup> in a short test to determine its suitability for the heavy ion fusion program. He used a  $7 \times 35 \text{ cm}^2$  area source with 100 slits, and obtained 9 amps of peak current at 30 kV extraction in 10 msec pulses. The beam is neutralized just after the source. The conference proceedings, Ref. 31, describes other possible heavy ion sources for heavy ion fusion, to produce 100 mA beam of mass 200, charge 1, for injection into a linear source, for 20 amps with mass 100, charge 1.5, for injection into an induction linac.

#### Laser, Vacuum Spark and Exploding Wire Sources

Several types of sources produce high charge state ions by dumping large pulses of energy into a target in short time periods. They are the laser, the vacuum spark, and the exploding wire. These sources are being used for studies such as spectroscopy of high charge state ions, usually without extraction of the ions to form a beam.

Laser sources were reviewed by Peacock.<sup>33</sup> Power densities up to  $5 \times 10^{14} \text{ w/cm}^2$  for about a nanosecond produced charge states of  $\text{Mg}^{11+}$ ,  $\text{Ti}^{20+}$ ,  $\text{Fe}^{23+}$ ,  $\text{Zn}^{27+}$ ,  $\text{W}^{50+}$ . In a summary paper<sup>34</sup> Nagel estimates that electron temperatures in plasmas produced by present lasers are about 1 keV, and that increases to the 10 keV range are expected with development of higher power lasers in the laser fusion program. In fact, ION Fusion, Inc. has reported<sup>35</sup> power densities of  $5 \times 10^{15} \text{ w/cm}^2$  on DT-filled glass microspheres. Silicon and oxygen ions coming off have an exponential energy distribution, with a calculated average energy of 1 keV/nucleon, assuming they are fully stripped. Other recent laser work is reported in other abstracts in Ref. 35.

The extraction of beams from laser-produced plasma was reviewed by Tonon.<sup>36</sup> The ion energies

corresponded to about 1 keV for a laser intensity of the plasma, with energy proportional to the laser intensity. Energy spread was about 20%. The repetition rate and thus duty factor, is small for present lasers.

The other types of pulsed sources are the vacuum spark and the exploding wire. The vacuum spark system at NBS<sup>37</sup> has a target of 14 kV, spark gap of 0.6 mm, 140 pF, and uses a 100 kV pulse generator. Charge states of  $\text{Ar}^{17+}$ ,  $\text{Zn}^{27+}$  and  $\text{W}^{50+}$  have been reported. The exploding wire source at NBS<sup>38</sup> has a 100 kV pulse generator and wire of 0.025 mm diameter. Charge states of  $\text{W}^{50+}$  and  $\text{Au}^{79+}$  have been reported. The charge state of the exploding wire plasma is  $\text{Cu}^{27+}$  and  $\text{Au}^{79+}$ . The laser-produced plasma is different but a similar plasma at NBS<sup>39</sup> has been reported for the production of ions.

#### Magnetic Field Ion Beam Source

Other workers in high charge state ions, such as the heavy plasma ion beam, development of the ion beam development unit at Lawrence Berkeley Laboratory, and the development of a cold particle beam have been proposed. This type of plasma was proposed and partially developed by Hainmueller, et al., in the HIFPA<sup>40</sup> for ion beam devices. Here it is proposed to use such a high charge state ion beam, which is produced every several seconds of ionization time, for development work stopped on this device.

#### Electron Ring Accelerator

In the first stage of an electron ring accelerator, a high intensity ring of electrons revolves in a confining magnetic field, and is capable of carrying the residual gas to high charge states. The ERA was reviewed by Peterson<sup>41</sup> and Langley.<sup>42</sup> In a study of Lawrence Berkeley Laboratory,<sup>43</sup> it was estimated that  $\text{Xe}^{50+}$  would be the mean charge state after one second in a high velocity electron ring of  $4 \times 10^{12}$  electrons, taking into account charge exchange with background  $\text{H}_2$  at  $10^{19} \text{ cm}^{-3}$ . Ions have been formed and accelerated in rings at NBS, U.S.S.R., and Germany, West Germany.

#### Linear Electron Beams

These were reviewed by Graybill,<sup>44</sup> Yano,<sup>45</sup> and Olson et al.<sup>47,48</sup> In these experiments electron beams of 10 kA to 1 MA and energies of 10 MeV and pulse lengths of 10-100 nsec are used. In the early experiments the beam passed through a guide tube filled with gas at 0.1 torr pressure. Graybill<sup>44</sup> reported the formation and acceleration of  $\text{Xe}^{50+}$  ions pulse of  $\text{N}^{14+}$ ,  $\text{S}^{16+}$  and  $\text{Ar}^{17+}$  to energies of 10-20 MeV. Other versions of electron beam ion source study or test include electron beam ion source in plasma, and in diodes. Experiments are described at this Conference by Olson et al. at the Sandia Laboratories on the Ionization Front Accelerator, in which ions are accelerated by a controlled, moving potential well of an intense electron beam. The ions are produced by laser photoionization of cesium gas. The development of electron beams for ionization and acceleration of ions is still in its early stages.

#### Stripping of Fast Ions

High charge state ions are produced by electron bombardment. In the sources of ions discussed in the previous sections the ions were moving slowly at around thermal velocities, and the electrons were moving at much higher velocities. Since it is the relative velocity of the electrons and ions which

quanta, the total charge states can also be produced by passing accelerated ions through a supersonic jet of gas, where the electrons have very low velocities. An analysis by Nagel<sup>54</sup> shows that a He atom ion has the same average charge state effect as a tripler as at ion in a plasma at various temperatures, assuming the original model for the plasma. A series of plots of some plasma sources available in a computer is given in Fig. 6. We note that the a) constant pressure very high temperature plasmas have the absolute state resistivity and the least separated head of one charge state which is useful for atomic spectroscopy, and the b) state of having high velocity, so that the charge states cannot be done at low energies. The plasma source behavior will open up a new area of study in the application of all masses.

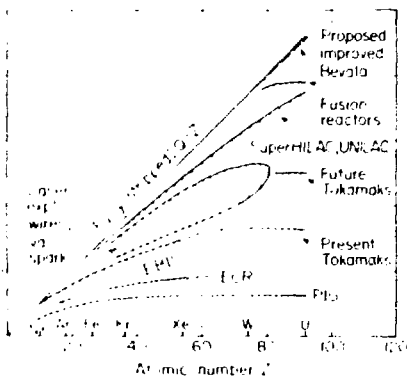


Fig. 6. Charge states available from ion sources. Tokamak and other plasmas, and stripping of accelerated beams.<sup>54,55</sup>

#### Negative Heavy Ion Sources

Negative heavy ion sources are used mostly for the production of tandem electrostatic accelerators. They were reviewed by Dawson,<sup>49</sup> Purser,<sup>50</sup> and Mather.<sup>51</sup> Negative ions normally have a charge of one or two charges, but a few ions such as oxygen, fluorine, and chlorine have been observed with a charge of three with intensities of about a nanoamp.

Negative heavy ions have been produced by several methods: charge exchange using incident or recoil ions, direct extraction, and by special sources such as the triplasma and the duodeneatron. The most important recent advance in negative heavy ion sources has been the development of sputter sources using cesium for bombardment or as surface coating. In the earliest source of this type built by the group of Horng,<sup>52</sup> the negative ions were sputtered by krypton from a wheel coated with cesium vapor. A later sputter source is the radial extracted EB, called SPIS and described by Smith.<sup>53</sup> Here the negative ions are sputtered out of the cathodes into the plasma. A source with similar geometry is the Aarhus ANIS,<sup>54</sup> a source in which the sputtering material is a concave spherical electrode placed opposite the extraction hole. Cesium is again necessary

for high sputtering yield. ANIS produced up to 30  $\mu$ A of Cs and 80  $\mu$ A of Au<sup>+</sup>.

One of the most successful of the sputtering sources is the UNIS source of Middleton.<sup>55</sup> He modified the Horng system into an axial design, shown in Fig. 7. In this source a cesium beam from a tungsten surface ionizer is accelerated to 20 kV. It strikes a hollow cone of the feed material, sputtering off negative ions which go through the hole of the cone and are accelerated. A wheel of 10 mm of different materials can rotate about the axis to give the axial quality. Gases can be fed in near the cone for these ions not available from the wall. The output includes a few  $\mu$ A of Au<sup>+</sup> and Bi<sup>+</sup> with a few  $\mu$ A of Cs<sup>+</sup>, O<sup>-</sup>, F<sup>-</sup>, S<sup>-</sup>, Se<sup>-</sup> and Cl<sup>-</sup>. All beams in the periodic table are expected to be available from this source, with the likely exception of He, Ag and Pt. A very similar source was built by Purser<sup>56</sup> at Rochester. The mechanism of ion formation for production is not fully understood, but is believed to be partly due to the presence of the wire function of the sputter surface.

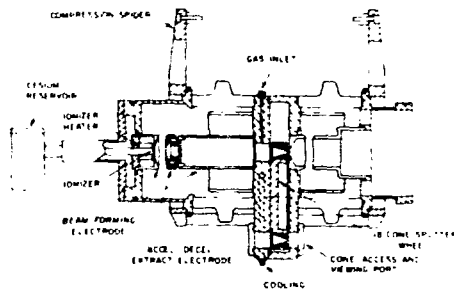


Fig. 7. Negative heavy ion source of Middleton<sup>55</sup> using Cs Sputtering of cone Material.

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